

Inventor Name Search Result

Your Search was:

Last Name = NAKAMURA

First Name = TOSHITAKA

Application#	Patent#	Status	Date Filed	Title	Inventor Name 10
<u>10477596</u>	Not Issued	019	01/01/0001	METHOD FOR TREATING OSTEOCHONDROSIS AND APPARATUS FOR TREATING OSTEOCHONDROSIS	NAKAMURA ET AL, TOSHITAKA
<u>10224598</u>	Not Issued	020	08/21/2002	STRUCTURE FOR PREVENTING GLASS FROM BREAKING AND PLASMA DISPLAY DEVICE	NAKAMURA, TOSHITAKA
<u>10145119</u>	Not Issued	061	05/15/2002	GLASS CRACK PREVENTION FILM-LIKE LAYER AND PLASMA DISPLAY DEVICE	NAKAMURA, TOSHITAKA
<u>09808104</u>	<u>6548177</u>	150	03/15/2001	TRANSPARENT SHOCK-ABSORBING LAMINATE AND FLAT PANEL DISPLAY USING THE SAME	NAKAMURA, TOSHITAKA
<u>09746228</u>	Not Issued	071	12/26/2000	TRANSPARENT LAMINATE, METHOD FOR PRODUCING THE SAME, AND PLASMA DISPLAY PANEL	NAKAMURA, TOSHITAKA
<u>09729785</u>	<u>6569516</u>	150	12/06/2000	TRANSPARENT LAMINATE AND PLASMA DISPLAY PANEL FILTER UTILIZING SAME	NAKAMURA, TOSHITAKA
<u>09608006</u>	<u>6398900</u>	150	06/30/2000	METHOD OF STICKING TRANSPARENT ELECTROMAGNETIC WAVE SHIELD FILM	NAKAMURA, TOSHITAKA
<u>09458805</u>	<u>6235398</u>	150	12/10/1999	TRANSPARENT LAMINATE AND PLASMA DISPLAY PANEL FILTER UTILIZING SAME	NAKAMURA, TOSHITAKA
<u>09455904</u>	<u>6252703</u>	150	12/07/1999	TRANSPARENT LAMINATE AND FILTER FOR USE FOR PLASMA DISPLAY PANEL USING THE TRANSPARENT LAMINATE	NAKAMURA, TOSHITAKA
<u>09404709</u>	<u>6333592</u>	150	09/24/1999	FILTER FOR PLASMA DISPLAY PANEL	NAKAMURA, TOSHITAKA

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Inventor Name Search Result

Your Search was:

Last Name = MIYAUCHI

First Name = KAZUHIKO

Application#	Patent#	Status	Date Filed	Title	Inventor Name 10
<u>10288441</u>	Not Issued	030	11/06/2002	GLASS-BREAK PREVENTING FILM LIKE FILTER AND PLASMA DISPLAY APPARATUS	MIYAUCHI, KAZUHIKO
<u>10274986</u>	Not Issued	030	10/22/2002	TRANSPARENT PRESSURE-SENSITIVE ADHESIVE COMPOSITION AND PRESSURE-SENSITIVE ADHESIVE SHEET THEREOF	MIYAUCHI, KAZUHIKO
<u>10224598</u>	Not Issued	020	08/21/2002	STRUCTURE FOR PREVENTING GLASS FROM BREAKING AND PLASMA DISPLAY DEVICE	MIYAUCHI, KAZUHIKO
<u>10145119</u>	Not Issued	061	05/15/2002	GLASS CRACK PREVENTION FILM-LIKE LAYER AND PLASMA DISPLAY DEVICE	MIYAUCHI, KAZUHIKO
<u>09808104</u>	<u>6548177</u>	150	03/15/2001	TRANSPARENT SHOCK-ABSORBING LAMINATE AND FLAT PANEL DISPLAY USING THE SAME	MIYAUCHI, KAZUHIKO
<u>09746228</u>	Not Issued	071	12/26/2000	TRANSPARENT LAMINATE, METHOD FOR PRODUCING THE SAME, AND PLASMA DISPLAY PANEL	MIYAUCHI, KAZUHIKO
<u>09729785</u>	<u>6569516</u>	150	12/06/2000	TRANSPARENT LAMINATE AND PLASMA DISPLAY PANEL FILTER UTILIZING SAME	MIYAUCHI, KAZUHIKO
<u>09608006</u>	<u>6398900</u>	150	06/30/2000	METHOD OF STICKING TRANSPARENT ELECTROMAGNETIC WAVE SHIELD FILM	MIYAUCHI, KAZUHIKO
<u>09458805</u>	<u>6235398</u>	150	12/10/1999	TRANSPARENT LAMINATE AND PLASMA DISPLAY PANEL FILTER UTILIZING SAME	MIYAUCHI, KAZUHIKO
<u>09455904</u>	<u>6252703</u>	150	12/07/1999	TRANSPARENT LAMINATE AND FILTER FOR USE FOR PLASMA DISPLAY PANEL USING THE TRANSPARENT LAMINATE	MIYAUCHI, KAZUHIKO

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KAZUHIKO

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Inventor Name Search Result

Your Search was:

Last Name = HIEDA

First Name = YOSHIHIRO

Application#	Patent#	Status	Date Filed	Title	Inventor Name 15
<u>10288441</u>	Not Issued	030	11/06/2002	GLASS-BREAK PREVENTING FILM LIKE FILTER AND PLASMA DISPLAY APPARATUS	HIEDA, YOSHIHIRO
<u>10274986</u>	Not Issued	030	10/22/2002	TRANSPARENT PRESSURE-SENSITIVE ADHESIVE COMPOSITION AND PRESSURE-SENSITIVE ADHESIVE SHEET THEREOF	HIEDA, YOSHIHIRO
<u>10224598</u>	Not Issued	020	08/21/2002	STRUCTURE FOR PREVENTING GLASS FROM BREAKING AND PLASMA DISPLAY DEVICE	HIEDA, YOSHIHIRO
<u>10145119</u>	Not Issued	061	05/15/2002	GLASS CRACK PREVENTION FILM-LIKE LAYER AND PLASMA DISPLAY DEVICE	HIEDA, YOSHIHIRO
<u>09808104</u>	<u>6548177</u>	150	03/15/2001	TRANSPARENT SHOCK-ABSORBING LAMINATE AND FLAT PANEL DISPLAY USING THE SAME	HIEDA, YOSHIHIRO
<u>09746228</u>	Not Issued	071	12/26/2000	TRANSPARENT LAMINATE, METHOD FOR PRODUCING THE SAME, AND PLASMA DISPLAY PANEL	HIEDA, YOSHIHIRO
<u>09729785</u>	<u>6569516</u>	150	12/06/2000	TRANSPARENT LAMINATE AND PLASMA DISPLAY PANEL FILTER UTILIZING SAME	HIEDA, YOSHIHIRO
<u>09608006</u>	<u>6398900</u>	150	06/30/2000	METHOD OF STICKING TRANSPARENT ELECTROMAGNETIC WAVE SHIELD FILM	HIEDA, YOSHIHIRO
<u>09458805</u>	<u>6235398</u>	150	12/10/1999	TRANSPARENT LAMINATE AND PLASMA DISPLAY PANEL FILTER UTILIZING SAME	HIEDA , YOSHIHIRO
<u>09455904</u>	<u>6252703</u>	150	12/07/1999	TRANSPARENT LAMINATE AND FILTER FOR USE FOR PLASMA DISPLAY PANEL USING THE TRANSPARENT LAMINATE	HIEDA , YOSHIHIRO
<u>08530249</u>	<u>5902768</u>	250	09/28/1997	REVERSIBLE HEAT-SENSITIVE RECORDING MATERIAL	HIEDA , YOSHIHIRO
<u>08281687</u>	<u>5472929</u>	150	07/28/1994	REVERSIBLE HEAT-SENSITIVE RECORDING MEDIUM AND	HIEDA , YOSHIHIRO

				MAGNETIC CARD USING THE SAME	
<u>08240528</u>	<u>5604175</u>	150	05/10/1994	REVERSIBLE HEAT-SENSITIVE RECORDING MEDIUM	HIEDA , YOSHIHIRO
<u>07925257</u>	<u>5258350</u>	150	08/06/1992	REVERSIBLE HEAT-SENSITIVE RECORDING MATERIAL AND MAGNETIC CARD USING THE SAME	HIEDA , YOSHIHIRO
<u>07732003</u>	<u>5229350</u>	150	07/18/1991	REVERSIBLE HEAT-SENSITIVE RECORDING MATERIAL AND MAGNETIC CARD USING THE RECORDING MATERIAL	HIEDA , YOSHIHIRO

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HIEDA	YOSHIHIRO

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Inventor Name Search Result

Your Search was:

Last Name = SASA

First Name = KAZUAKI

Application#	Patent#	Status	Date Filed	Title	Inventor Name 51
<u>10471103</u>	Not Issued	020	09/08/2003	COMPLEX CATALYST, PROCESS FOR PRODUCING THE COMPLEX CATALYST, AND PROCESS FOR PRODUCING ALCHOHOL DERIVATIVE WITH THE COMPLEX CATALYST	SASAKI, KAZUAKI
<u>10407421</u>	Not Issued	030	04/07/2003	TRANSPARENT CONDUCTIVE LAMINATE AND PROCESS OF PRODUCING THE SAME	SASA, KAZUAKI
<u>10304710</u>	Not Issued	030	11/27/2002	SEMICONDUCTOR LIGHT-EMITTING DEVICE	SASAKI, KAZUAKI
<u>10253609</u>	Not Issued	041	09/25/2002	SEMICONDUCTOR LIGHT-EMITTING DEVICE AND METHOD FOR MANUFACTURING THEREOF	SASAKI, KAZUAKI
<u>10198178</u>	Not Issued	030	07/19/2002	MEDICINE, CARRIER FOR MEDICINE, METHOD OF PRODUCING MEDICINE, AND METHOD OF TUMOR TREATMENT	SASAKI, KAZUAKI
<u>10189627</u>	Not Issued	061	07/08/2002	FABRICATION METHOD OF SEMICONDUCTOR LIGHT-EMITTING DEVICE	SASAKI, KAZUAKI
<u>10083575</u>	Not Issued	041	02/27/2002	METHOD FOR PRODUCING OPTICALLY ACTIVE CHRYSANTHEMIC ACID	SASAKI, KAZUAKI
<u>10075284</u>	Not Issued	041	02/15/2002	THERAPEUTIC ULTRASOUND SYSTEM	SASAKI, KAZUAKI
<u>09839114</u>	<u>6399409</u>	150	04/23/2001	METHOD FOR FABRICATING SEMICONDUCTOR LIGHT EMITTING ELEMENT	SASAKI, KAZUAKI
<u>09838592</u>	<u>6476421</u>	150	04/20/2001	SEMICONDUCTOR LIGHT-EMITTING DEVICE AND METHOD FOR MANUFACTURING THEREOF	SASAKI, KAZUAKI
<u>09830423</u>	<u>6511428</u>	150	04/26/2001	ULTRASONIC MEDICAL TREATING DEVICE	SASAKI, KAZUAKI
<u>09801844</u>	<u>6572839</u>	150	03/09/2001	SENSITIZER FOR TUMOR TREATMENT	SASAKI, KAZUAKI
<u>09757689</u>	<u>6399965</u>	150	01/11/2001	SEMICONDUCTOR LIGHT EMITTING DEVICE WITH HIGH YIELD AND LOW POWER CONSUMPTION	SASAKI, KAZUAKI

<u>09746228</u>	Not Issued	071	12/26/2000	TRANSPARENT LAMINATE, METHOD FOR PRODUCING THE SAME, AND PLASMA DISPLAY PANEL	SASA, KAZUAKI
<u>09729785</u>	6569516	150	12/06/2000	TRANSPARENT LAMINATE AND PLASMA DISPLAY PANEL FILTER UTILIZING SAME	SASA, KAZUAKI
<u>09671777</u>	6465812	150	09/27/2000	SEMICONDUCTOR LIGHT EMITTING DEVICE	SASAKI, KAZUAKI
<u>09608006</u>	6398900	150	06/30/2000	METHOD OF STICKING TRANSPARENT ELECTROMAGNETIC WAVE SHIELD FILM	SASA, KAZUAKI
<u>09490534</u>	6468818	150	01/25/2000	METHOD FOR PRODUCING A HIGH-LUMINANCE SEMICONDUCTOR LIGHT- EMITTING DEVICE CAPABLE OF OPERATING AT A LOW VOLTAGE	SASAKI, KAZUAKI
<u>09458805</u>	6235398	150	12/10/1999	TRANSPARENT LAMINATE AND PLASMA DISPLAY PANEL FILTER UTILIZING SAME	SASA , KAZUAKI
<u>09455904</u>	6252703	150	12/07/1999	TRANSPARENT LAMINATE AND FILTER FOR USE FOR PLASMA DISPLAY PANEL USING THE TRANSPARENT LAMINATE	SASA , KAZUAKI
<u>09404709</u>	6333592	150	09/24/1999	FILTER FOR PLASMA DISPLAY PANEL	SASA , KAZUAKI
<u>09238503</u>	6268525	150	01/27/1999	PROCESS FOR PRODUCING OPTICALLY ACTIVE CHRYSANTHEMIC ACID	SASAKI , KAZUAKI
<u>09205184</u>	6074889	150	12/04/1998	METHOD FOR PRODUCING SEMICONDUCTOR LIGHT- EMITTING DEVICE WITH UNDOPED SPACER LAYER	SASAKI , KAZUAKI
<u>09015052</u>	6246078	150	01/28/1998	SEMICONDUCTOR LIGHT EMITTING ELEMENT	SASAKI , KAZUAKI
<u>08742695</u>	6216538	150	11/04/1996	PARTICLE HANDLING APPARATUS FOR HANDLING PARTICLES IN FLUID BY ACOUSTIC RADIATION PRESSURE	SASAKI , KAZUAKI
<u>08668086</u>	5717709	150	06/19/1996	SEMICONDUCTOR LIGHT- EMITTING DEVICE CAPABLE OF HAVING GOOD STABILITY IN FUNDAMENTAL MODE OF OSCILLATION, DECREASING CURRENT LEAKAGE, AND LOWERING OSCILLATION THRESHOLD LIMIT, AND METHOD OF MAKING THE SAME	SASAKI , KAZUAKI
<u>08652357</u>	5856682	150	05/23/1996	SEMICONDUCTOR LIGHT- EMITTING DEVICE AND METHOD FOR PRODUCING THE SAME	SASAKI , KAZUAKI

<u>08435391</u>	<u>5516723</u>	150	05/05/1995	SEMICONDUCTOR LIGHT-EMITTING DEVICE CAPABLE OF HAVING GOOD STABILITY IN FUNDAMENTAL MODE OF OSCILLATION, DECREASING CURRENT LEAKAGE, AND LOWERING OSCILLATION THRESHOLD LIMIT, AND METHOD OF MAKING THE SAME	SASAKI , KAZUAKI
<u>08409067</u>	Not Issued	161	03/23/1995	ALDOL CONDENSATION DEHYDRATION AND CATALYST THEREFOR	SASAKI , KAZUAKI
<u>08314585</u>	<u>5571750</u>	150	09/28/1994	METHOD FOR PRODUCING A SEMICONDUCTOR LASER DEVICE	SASAKI , KAZUAKI
<u>08270115</u>	<u>5404031</u>	150	07/01/1994	SEMICONDUCTOR LIGHT EMITTING DEVICE WITH CURRENT CONFINING LAYER	SASAKI , KAZUAKI
<u>08253363</u>	Not Issued	166	06/03/1994	SEMICONDUCTOR LIGHT-EMITTING DEVICE CAPABLE OF HAVING GOOD STABILITY IN FUNDAMENTAL MODE OF OSCILLATION, DECREASING CURRENT LEAKAGE, AND LOWERING OSCILLATION THRESHOLD LIMIT, AND METHOD OF MAKING THE SAME	SASAKI , KAZUAKI
<u>08163290</u>	Not Issued	166	12/02/1993	PARTICLE HANDLING APPARATUS FOR HANDLING PARTICLES IN FLUID BY ACOUSTIC RADIATION PRESSURE	SASAKI , KAZUAKI
<u>08148329</u>	Not Issued	161	11/08/1993	ALDOL CONDENSATION DEHYDRATION AND CATALYST THEREFOR	SASAKI , KAZUAKI
<u>08056906</u>	Not Issued	161	05/05/1993	MAGNESIUM ALUMINIUM COMPLEX COMPOUNDS, PROCESS FOR PREPARING THE SAME AND PROCESS OF ALDOL CONDENSATION DEHYDRATION PRODUCTS USING THE SAME	SASAKI , KAZUAKI
<u>08025434</u>	Not Issued	166	03/03/1993	SEMICONDUCTOR LIGHT EMITTING DEVICE	SASAKI , KAZUAKI
<u>07998436</u>	<u>5260231</u>	150	12/30/1992	METHOD FOR THE PRODUCTION OF A SEMICONDUCTOR LASER	SASAKI , KAZUAKI
<u>07995064</u>	<u>5413956</u>	150	12/22/1992	METHOD FOR PRODUCING A SEMICONDUCTOR LASER DEVICE	SASAKI , KAZUAKI
<u>07980666</u>	<u>5309001</u>	150	11/24/1992	LIGHT-EMITTING DIODE HAVING A SURFACE ELECTRODE OF A TREE-LIKE FORM	SASAKI , KAZUAKI
<u>07883397</u>	<u>5243081</u>	150	05/15/1992	ALDOL CONDENSATION DEHYDRATION CATALYST, A PROCESS FOR PREPARING THE SAME AND A PROCESS FOR	SASAKI , KAZUAKI

				PREPARING AN ALDOL CONDENSATION DEHYDRATE USING THE PROCESS	
<u>07879583</u>	<u>5237107</u>	150	05/07/1992	MAGNESIUM. ALUMINIUM COMPLEX COMPOUNDS, PROCESS FOR PREPARING THE SAME AND PROCESS OF ALDOL CONDENSATION DEHYDRATION PRODUCTS USING THE SAME	SASAKI , KAZUAKI
<u>07762769</u>	<u>5228047</u>	150	09/20/1991	SEMICONDUCTOR LASER DEVICE AND A METHOD FOR PRODUCING THE SAME	SASAKI , KAZUAKI
<u>07739767</u>	<u>5171706</u>	150	08/01/1991	METHOD FOR THE PRODUCTION OF A SEMICONDUCTOR LASER DEVICE	SASAKI , KAZUAKI
<u>07727375</u>	<u>5208468</u>	150	07/05/1991	SEMICONDUCTOR LASER DEVICE WITH A SULFUR-CONTAINING FILM PROVIDED BETWEEN THE FACET AND THE PROTECTIVE FILM	SASAKI , KAZUAKI
<u>07513508</u>	<u>5042044</u>	150	04/27/1990	SEMICONDUCTOR LASER DEVICE, A SEMICONDUCTOR WAFER	SASAKI , KAZUAKI
<u>07474272</u>	Not Issued	166	02/02/1990	SEMICONDUCTOR LASER DEVICE AND A METHOD FOR THE PRODUCTION OF THE SAME	SASAKI , KAZUAKI
<u>07456673</u>	<u>5022036</u>	150	12/27/1989	SEMICONDUCTOR LASER DEVICE	SASAKI , KAZUAKI
<u>07406903</u>	<u>4984244</u>	250	09/13/1989	SEMICONDUCTOR LASER DEVICE	SASAKI , KAZUAKI
<u>07347099</u>	Not Issued	166	05/03/1989	METHOD FOR THE PRODUCTION OF SEMICONDUCTOR DEVICES	SASAKI , KAZUAKI
<u>07286682</u>	<u>4977568</u>	150	12/19/1988	SEMICONDUCTOR LASER DEVICE	SASAKI , KAZUAKI
<u>06534868</u>	<u>4592623</u>	150	09/22/1983	POLARIZING PLATE	SASA , KAZUAKI

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L Number	Hits	Search Text	DB	Time stamp
1	1	6548177.pn.	USPAT; US-PGPUB	2004/01/12 09:09
2	57	(Nakamura.in. or Sasa.in. or Hieda.in. or Miyauchi.in. or (Nitto adj Denko).as.) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag or (transparent near2 conduct\$3)) with (temperature))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/12 09:16
3	11	(Nakamura.in. or Sasa.in. or Hieda.in. or Miyauchi.in. or (Nitto adj Denko).as.) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag or (transparent near2 conduct\$3)) with (rate near2 (deposit\$3)))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/12 09:17
4	82	(Nakamura.in. or Sasa.in. or Hieda.in. or Miyauchi.in. or (Nitto adj Denko).as.) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index))))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/12 09:49
5	52	(Nakamura.in. or Sasa.in. or Hieda.in. or Miyauchi.in. or (Nitto adj Denko).as.) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) same ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index))))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/12 09:21
6	14	((Nakamura.in. or Sasa.in. or Hieda.in. or Miyauchi.in. or (Nitto adj Denko).as.) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))) and (PDP or (plasma adj display)))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/12 09:19
7	42	((Nakamura.in. or Sasa.in. or Hieda.in. or Miyauchi.in. or (Nitto adj Denko).as.) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) same ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))) not (((Nakamura.in. or Sasa.in. or Hieda.in. or Miyauchi.in. or (Nitto adj Denko).as.) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))) and (PDP or (plasma adj display)))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/12 09:22
8	726	(427/108,109).CCLS.	USPAT; US-PGPUB	2004/01/12 09:22
9	1505	(427/124,125).CCLS.	USPAT; US-PGPUB	2004/01/12 09:22
10	1956	(427/163.1,164,165,166).CCLS.	USPAT; US-PGPUB	2004/01/12 09:23
11	2418	(427/250,255.32,255.7).CCLS.	USPAT; US-PGPUB	2004/01/12 09:23
12	2325	(427/404,419.1,419.2,419.3).CCLS.	USPAT; US-PGPUB	2004/01/12 09:23
13	686	(204/192.1,192.14).CCLS.	USPAT; US-PGPUB	2004/01/12 09:23
14	1991	(204/192.15,192.26,192.28).CCLS.	USPAT; US-PGPUB	2004/01/12 09:24

15	1103	(313/112,489).CCLS.	USPAT; US-PGPUB	2004/01/12 09:24
16	2352	(359/359,360,580,586,588,885,888).CCLS.	USPAT; US-PGPUB	2004/01/12 09:24
17	12990	((427/108,109).CCLS.) ((427/124,125).CCLS.) ((427/163.1,164,165,166).CCLS.) ((427/250,255.32,255.7).CCLS.) ((427/404,419.1,419.2,419.3).CCLS.) ((204/192.1,192.14).CCLS.) ((204/192.15,192.26,192.28).CCLS.) ((313/112,489).CCLS.) ((359/359,360,580,586,588,885,888).CCLS.) ((204/192.15,192.26,192.28).CCLS.) and (((313/112,489).CCLS.) or ((359/359,360,580,586,588,885,888).CCLS.)) (((427/108,109).CCLS.) ((427/124,125).CCLS.) ((427/163.1,164,165,166).CCLS.) ((427/250,255.32,255.7).CCLS.) ((427/404,419.1,419.2,419.3).CCLS.) ((204/192.1,192.14).CCLS.) ((204/192.15,192.26,192.28).CCLS.) ((313/112,489).CCLS.) ((359/359,360,580,586,588,885,888).CCLS.)) and ((sputter\$3 or (vacuum adj dry)) with (Ag or silver) with (temperature)) ((sputter\$3 or (vacuum adj dry)) with (Ag or silver) with (temperature)) (((sputter\$3 or (vacuum adj dry)) with (Ag or silver) with (temperature))) not (((427/108,109).CCLS.) ((427/124,125).CCLS.) ((427/163.1,164,165,166).CCLS.) ((427/250,255.32,255.7).CCLS.) ((427/404,419.1,419.2,419.3).CCLS.) ((204/192.1,192.14).CCLS.) ((204/192.15,192.26,192.28).CCLS.) ((313/112,489).CCLS.) ((359/359,360,580,586,588,885,888).CCLS.)) and ((sputter\$3 or (vacuum adj dry)) with (Ag or silver) with (temperature))) ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))) and (((427/108,109).CCLS.) ((427/124,125).CCLS.) ((427/163.1,164,165,166).CCLS.) ((427/250,255.32,255.7).CCLS.) ((427/404,419.1,419.2,419.3).CCLS.) ((204/192.1,192.14).CCLS.) ((204/192.15,192.26,192.28).CCLS.) ((313/112,489).CCLS.) ((359/359,360,580,586,588,885,888).CCLS.))	USPAT; US-PGPUB USPAT; US-PGPUB	2004/01/12 09:25
18	38	((313/112,489).CCLS.) or ((359/359,360,580,586,588,885,888).CCLS.))	USPAT; US-PGPUB	2004/01/12 09:27
19	20	((427/108,109).CCLS.) ((427/124,125).CCLS.) ((427/163.1,164,165,166).CCLS.) ((427/250,255.32,255.7).CCLS.) ((427/404,419.1,419.2,419.3).CCLS.) ((204/192.1,192.14).CCLS.) ((204/192.15,192.26,192.28).CCLS.) ((313/112,489).CCLS.) ((359/359,360,580,586,588,885,888).CCLS.))	USPAT; US-PGPUB	2004/01/12 09:33
20	168	((sputter\$3 or (vacuum adj dry)) with (Ag or silver) with (temperature))	USPAT; US-PGPUB	2004/01/12 09:33
21	148	((sputter\$3 or (vacuum adj dry)) with (Ag or silver) with (temperature))) not (((427/108,109).CCLS.) ((427/124,125).CCLS.) ((427/163.1,164,165,166).CCLS.) ((427/250,255.32,255.7).CCLS.) ((427/404,419.1,419.2,419.3).CCLS.) ((204/192.1,192.14).CCLS.) ((204/192.15,192.26,192.28).CCLS.) ((313/112,489).CCLS.) ((359/359,360,580,586,588,885,888).CCLS.)) and ((sputter\$3 or (vacuum adj dry)) with (Ag or silver) with (temperature))) ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))) and (((427/108,109).CCLS.) ((427/124,125).CCLS.) ((427/163.1,164,165,166).CCLS.) ((427/250,255.32,255.7).CCLS.) ((427/404,419.1,419.2,419.3).CCLS.) ((204/192.1,192.14).CCLS.) ((204/192.15,192.26,192.28).CCLS.) ((313/112,489).CCLS.) ((359/359,360,580,586,588,885,888).CCLS.))	USPAT; US-PGPUB USPAT; US-PGPUB	2004/01/12 09:33
22	253	((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))) and (((427/108,109).CCLS.) ((427/124,125).CCLS.) ((427/163.1,164,165,166).CCLS.) ((427/250,255.32,255.7).CCLS.) ((427/404,419.1,419.2,419.3).CCLS.) ((204/192.1,192.14).CCLS.) ((204/192.15,192.26,192.28).CCLS.) ((313/112,489).CCLS.) ((359/359,360,580,586,588,885,888).CCLS.))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/12 10:02

23	248	(((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))) and (((427/108,109).CCLS.) ((427/124,125).CCLS.) ((427/163.1,164,165,166).CCLS.) ((427/250,255.32,255.7).CCLS.) ((427/404,419.1,419.2,419.3).CCLS.) ((204/192.1,192.14).CCLS.) ((204/192.15,192.26,192.28).CCLS.) ((313/112,489).CCLS.) ((359/359,360,580,586,588,885,888).CCLS.))) not ((Nakamura.in. or Sasa.in. or Hieda.in. or Miyauchi.in. or (Nitto adj Denko).as.) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) same ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index))))))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/12 09:50
24	30	(((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))) and (((427/108,109).CCLS.) ((427/124,125).CCLS.) ((427/163.1,164,165,166).CCLS.) ((427/250,255.32,255.7).CCLS.) ((427/404,419.1,419.2,419.3).CCLS.) ((204/192.1,192.14).CCLS.) ((204/192.15,192.26,192.28).CCLS.) ((313/112,489).CCLS.) ((359/359,360,580,586,588,885,888).CCLS.))) not ((Nakamura.in. or Sasa.in. or Hieda.in. or Miyauchi.in. or (Nitto adj Denko).as.) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) same ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index))))))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/12 09:51
25	102	and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))) and (((427/108,109).CCLS.) ((427/124,125).CCLS.) ((427/163.1,164,165,166).CCLS.) ((427/250,255.32,255.7).CCLS.) ((427/404,419.1,419.2,419.3).CCLS.) ((204/192.1,192.14).CCLS.) ((204/192.15,192.26,192.28).CCLS.) ((313/112,489).CCLS.) ((359/359,360,580,586,588,885,888).CCLS.))) and ((sputter\$3 or deposit\$3) with temperature)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/12 09:58

26	154	((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))) and (((427/108,109).CCLS.) ((427/124,125).CCLS.) ((427/163.1,164,165,166).CCLS.) ((427/250,255.32,255.7).CCLS.) ((427/404,419.1,419.2,419.3).CCLS.) ((204/192.1,192.14).CCLS.) ((204/192.15,192.26,192.28).CCLS.) ((313/112,489).CCLS.) ((359/359,360,580,586,588,885,888).CCLS.))) and ((sputter\$3 or deposit\$3 or coat\$3) with temperature)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/12 09:59
27	135	((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))) and (((427/108,109).CCLS.) ((427/124,125).CCLS.) ((427/163.1,164,165,166).CCLS.) ((427/250,255.32,255.7).CCLS.) ((427/404,419.1,419.2,419.3).CCLS.) ((204/192.1,192.14).CCLS.) ((204/192.15,192.26,192.28).CCLS.) ((313/112,489).CCLS.) ((359/359,360,580,586,588,885,888).CCLS.))) and ((sputter\$3 or deposit\$3 or coat\$3) with temperature)) not (((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))) and (((427/108,109).CCLS.) ((427/124,125).CCLS.) ((427/163.1,164,165,166).CCLS.) ((427/250,255.32,255.7).CCLS.) ((427/404,419.1,419.2,419.3).CCLS.) ((204/192.1,192.14).CCLS.) ((204/192.15,192.26,192.28).CCLS.) ((313/112,489).CCLS.) ((359/359,360,580,586,588,885,888).CCLS.))) not ((Nakamura.in. or Sasa.in. or Hieda.in. or Miyauchi.in. or (Nitto adj Denko).as.) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) same ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))) and (((427/108,109).CCLS.) ((427/124,125).CCLS.) ((427/163.1,164,165,166).CCLS.) ((427/250,255.32,255.7).CCLS.) ((427/404,419.1,419.2,419.3).CCLS.) ((204/192.1,192.14).CCLS.) ((204/192.15,192.26,192.28).CCLS.) ((313/112,489).CCLS.) ((359/359,360,580,586,588,885,888).CCLS.))) and ((sputter\$3 or deposit\$3 or coat\$3) with temperature)) and ((sputter\$3 with temperature))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/12 09:58
28	47	and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))) and (((427/108,109).CCLS.) ((427/124,125).CCLS.) ((427/163.1,164,165,166).CCLS.) ((427/250,255.32,255.7).CCLS.) ((427/404,419.1,419.2,419.3).CCLS.) ((204/192.1,192.14).CCLS.) ((204/192.15,192.26,192.28).CCLS.) ((313/112,489).CCLS.) ((359/359,360,580,586,588,885,888).CCLS.))) and ((sputter\$3 or deposit\$3 or coat\$3) with temperature)) and ((sputter\$3 with temperature))	USPAT; US-PGPUB	2004/01/12 09:59

29	186	((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) same ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))) same (repeat\$3 or multilayer or (multi adj layer) or (multiple adj layer) or (PDP) or (plasma adj display) or filter or stack))	USPAT; US-PGPUB	2004/01/12 10:10
30	27	((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) same ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))) same (repeat\$3 or multilayer or (multi adj layer) or (multiple adj layer) or (PDP) or (plasma adj display) or filter or stack)) and (((427/108,109).CCLS.) ((427/124,125).CCLS.) ((427/163.1,164,165,166).CCLS.) ((427/250,255.32,255.7).CCLS.) ((427/404,419.1,419.2,419.3).CCLS.) ((204/192.1,192.14).CCLS.) ((204/192.15,192.26,192.28).CCLS.) ((313/112,489).CCLS.) ((359/359,360,580,586,588,885,888).CCLS.))	USPAT; US-PGPUB	2004/01/12 10:06
31	14	((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) same ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))) same (repeat\$3 or multilayer or (multi adj layer) or (multiple adj layer) or (PDP) or (plasma adj display) or filter or stack)) and ((sputter\$3 or (vacuum adj (dry or deposit\$3)) or PVD) with temperature)	USPAT; US-PGPUB	2004/01/12 10:19
32	1844	((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) same ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))))	USPAT; US-PGPUB	2004/01/12 10:14
33	134	((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) same ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index))))) and ((sputter\$3 or (vacuum adj (dry or deposit\$3)) or PVD) with temperature)	USPAT; US-PGPUB	2004/01/12 10:10
34	120	((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) same ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index))))) and ((sputter\$3 or (vacuum adj (dry or deposit\$3)) or PVD) with temperature)) not (((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) same ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))) same (repeat\$3 or multilayer or (multi adj layer) or (multiple adj layer) or (PDP) or (plasma adj display) or filter or stack)) and ((sputter\$3 or (vacuum adj (dry or deposit\$3)) or PVD) with temperature))	USPAT; US-PGPUB	2004/01/12 10:10

35	386	((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3 or PVD) with (silver or Ag)) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3 or PVD) with ((high near2 (refract\$3 near2 index)))))	USPAT; US-PGPUB	2004/01/12 10:14
36	114	((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3 or PVD) with (silver or Ag)) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3 or PVD) with ((high near2 (refract\$3 near2 index))))) and (((427/108,109).CCLS.) ((427/124,125).CCLS.) ((427/163.1,164,165,166).CCLS.) ((427/250,255.32,255.7).CCLS.) ((427/404,419.1,419.2,419.3).CCLS.) ((204/192.1,192.14).CCLS.) ((204/192.15,192.26,192.28).CCLS.) ((313/112,489).CCLS.) ((359/359,360,580,586,588,885,888).CCLS.))	USPAT; US-PGPUB	2004/01/12 10:15

37	103	<p>(((((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3 or PVD) with (silver or Ag)) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3 or PVD) with ((high near2 (refract\$3 near2 index)))))) and (((427/108,109).CCLS.) ((427/124,125).CCLS.) ((427/163.1,164,165,166).CCLS.) ((427/250,255.32,255.7).CCLS.) ((427/404,419.1,419.2,419.3).CCLS.) ((204/192.1,192.14).CCLS.) ((204/192.15,192.26,192.28).CCLS.) ((313/112,489).CCLS.) ((359/359,360,580,586,588,885,888).CCLS.))) not ((((((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) same ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))))) and ((sputter\$3 or (vacuum adj (dry or deposit\$3)) or PVD) with temperature)) not ((((((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) same ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))) same (repeat\$3 or multilayer or (multi adj layer) or (multiple adj layer) or (PDP) or (plasma adj display) or filter or stack))) and ((sputter\$3 or (vacuum adj (dry or deposit\$3)) or PVD) with temperature))) or ((((((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) same ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))) same (repeat\$3 or multilayer or (multi adj layer) or (multiple adj layer) or (PDP) or (plasma adj display) or filter or stack))) and (((427/108,109).CCLS.) ((427/124,125).CCLS.) ((427/163.1,164,165,166).CCLS.) ((427/250,255.32,255.7).CCLS.) ((427/404,419.1,419.2,419.3).CCLS.) ((204/192.1,192.14).CCLS.) ((204/192.15,192.26,192.28).CCLS.) ((313/112,489).CCLS.) ((359/359,360,580,586,588,885,888).CCLS.))) or ((((((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) same ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))) same (repeat\$3 or multilayer or (multi adj layer) or (multiple adj layer) or (PDP) or (plasma adj display) or filter or stack))) and ((sputter\$3 or (vacuum adj (dry or deposit\$3)) or PVD) with temperature)))</p>	USPAT; US-PGPUB	2004/01/12 10:15
38	33	<p>(((((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3 or PVD) with (silver or Ag)) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3 or PVD) with ((high near2 (refract\$3 near2 index)))))) and ((sputter\$3 or (vacuum adj (dry or deposit\$3)) or PVD) with temperature))</p>	USPAT; US-PGPUB	2004/01/12 10:21

39	30	(((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3 or PVD) with (silver or Ag)) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3 or PVD) with ((high near2 (refract\$3 near2 index))))) and ((sputter\$3 or (vacuum adj (dry or deposit\$3)) or PVD) with temperature)) not (((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) same ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))) same (repeat\$3 or multilayer or (multi adj layer) or (multiple adj layer) or (PDP) or (plasma adj display) or filter or stack))) and ((sputter\$3 or (vacuum adj (dry or deposit\$3)) or PVD) with temperature))	USPAT; US-PGPUB	2004/01/12 10:19
40	291	((sputter\$3 or (vacuum adj (dry or deposit\$3)) or PVD) with temperature) and (Ag or silver)	EPO; JPO; DERWENT; IBM_TDB	2004/01/12 10:25
41	92	((sputter\$3 or (vacuum adj (dry or deposit\$3)) or PVD) with temperature) with (Ag or silver)	EPO; JPO; DERWENT; IBM_TDB	2004/01/12 10:21
42	22	((sputter\$3 or (vacuum adj (dry or deposit\$3)) or PVD) with temperature) and (Ag or silver)) and (multilayer or (multi adj layer) or stack or filter or PDP or (plasma adj display))	EPO; JPO; DERWENT; IBM_TDB	2004/01/12 10:26